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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Attn: OIPE

Masakazu SATO et al.

Application No.: 10/517,655

Docket No.: 122035

Filed: December 13, 2004

For: METHOD OF EVALUATING SHAPE OF SEMICONDUCTOR WAFER AND
APPARATUS FOR EVALUATING SHAPE OF SEMICONDUCTOR WAFER

REQUEST FOR CORRECTION OF PALM RECORDS

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Attached is a photocopy of the original filing receipt on which errors have been corrected in red. These errors are being brought to the attention of the Patent and Trademark Office so that it may correct its records.

Respectfully submitted,

William P. Berridge
Registration No. 30,024

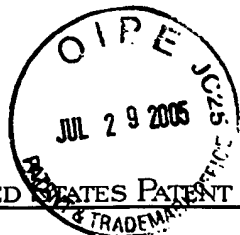
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WPB:JOC/emt

Date: July 29, 2005

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|------------|---------------------------|----------|---------------|-----------------|----------|----------|----------|
| 10/517,655 | 12/13/2004 | 2812 | 6600 | 122035 | 8 | 132 | 2 |

CONFIRMATION NO. 7281

25944
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FILING RECEIPT



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Applicant(s)

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Assignment For Published Patent Application

SHIN-ETSU HANDOTAI CO LTD, Chiyoda-ku, JAPAN

Power of Attorney: The patent practitioners associated with Customer Number 25944.

Domestic Priority data as claimed by applicant

This application is a 371 of PCT/JP03/07320 06/10/2003

Foreign Applications

JAPAN 2002173268 06/11/2002

Projected Publication Date: 09/22/2005

Non-Publication Request: No

Early Publication Request: No

Title

~~Semiconductor wafer shape evaluating method and shape evaluating device~~

Preliminary Class 438 Method of Evaluating Shape of Semiconductor Wafer and Apparatus for Evaluating Shape of Semiconductor Wafer

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